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(71)Applicant : HITACHI LTD

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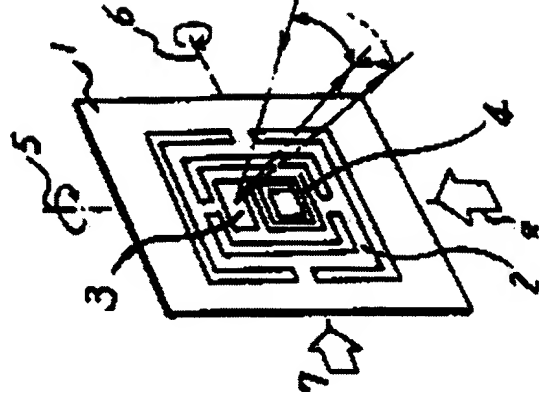
(72)Inventor : TANABE MASANORI
 KAWAKAMI HIROJI
 SHIMADA SATOSHI
 YAMADA KAZUJI

(54) OPTICAL DEFLECTING ELEMENT

(57)Abstract:

PURPOSE: To make a two-dimensional deflection scan through one element by supporting a galvano mirror with a gimbal spring, and controlling the application of magnetic fields in two X and Y directions while flowing a current to the thin film coil on a mirror surface.

CONSTITUTION: A substrate 1 made of Si single crystal is worked into the gimbal spring by photoengraving. The gimbal spring 2 rotates and oscillates about an X-directional axis 5 and an Y-directional axis 6 independently. The galvano mirror 3 and thin film coil 4 are formed on the surface of the center movable part of the substrate 1 supported with the gimbal spring 2 by metal vapor deposition or plating. The constant current is supplied to the thin film coil 4 to vary a magnetic field 7 in the X



direction and a magnetic field 8 in the Y direction independently of each other, and consequently the element rotates and oscillates about the axes 5 and 6 independently of each other with electromagnetic force, so that reflected light from the mirror 3 is deflected in two dimensions.

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